

Description

The invention relates to an arrangement comprising a space which is evacuated or filled with a protective gas, this arrangement having an electron-emitting body, which can be coated at an electron-emitting surface from a reservoir with material reducing the electron work function situated within the space.

The electron-emitting body may be a thermionic cathode, for example in a vacuum tube, but may especially be a semiconductor cathode; in the latter case, various kinds of semiconductor cathodes may be used, such as NEA cathodes, field emitters and more particularly reverse junction cathodes, as described in Netherlands Patent Application No. 7 905 470 in the name of the Applicant. Such vacuum tubes are suitable to be used as camera tubes or display tubes, but may also be used in apparatus for Auger spectroscopy, electron microscopy and electron lithography.

The arrangement concerned may also be provided with a photocathode, incident radiation leading to an electron current which leaves the photocathode. Such photocathodes are used in photocells, camera tubes, image converters and photomultiplier tubes. Another application of an arrangement according to the invention resides in so-called thermionic converters, in which thermal radiation is converted into an electron current.

The invention further relates to a reservoir for such an arrangement.

An arrangement as mentioned above is known from Journal of Applied Physics 51 (1980), No. 6, pages 3404-3408.

In the arrangement shown in this article, a quantity of caesium is periodically introduced into the vacuum space. If use is made of a semiconductor cathode, this caesium will cover the emitting surface as a mono-atomic layer, after which reduction of the quantity of caesium on the emitting surface is only compensated for in a rather uncontrollable way. Such a reduction of caesium or another material reducing the electron work function at the surface is due *inter alia* to desorption and migration under the influence of electric fields and gives rise to degradation of emission. The ultimate efficiency of, for example, a reverse biased junction cathode thus remains limited to 20 to 40% of the optimum value.

The invention has for its object to provide an arrangement, in which the aforementioned problems are eliminated at least in part and in which device a source of material reducing the work function is coupled to the vacuum space, while the supply of material reducing the work function from this source to the emitting surface can be regulated in a very accurate way.

An arrangement according to the invention is for this purpose, characterized in that the reservoir comprises two compartments, which communicate with each other through at least one opening in an intermediate wall, one compartment accommodating the source of material reducing the electron work function and the other compartment being provided with at least one exit opening, through which the ma-

terial reducing the work function can leave the reservoir.

In such an arrangement the supply of electron work function reducing material from the reservoir can be regulated in a simple manner, for example, in the case of caesium by regulating the rate of evaporation by means of heating and cooling means or by mechanically adjusting the opening in the intermediate wall.

By choosing a suitable dimension of the exit opening(s), it can moreover be achieved that only a small quantity of the evaporated material (for example caesium) reaches the vacuum space, which quantity is sufficient, however, to attain the desired effect (compensation of the loss of caesium due to desorption and migration). This has the advantage that the actual vacuum space and the deflection electrodes (and other component parts) present therein, are not or substantially not contaminated by the caesium (or another material reducing the work function), which has a favourable influence on the high-voltage properties of the vacuum tube and the components present therein.

The last-mentioned effect can be further increased when the first acceleration grid is constructed so that the space in which the cathode is situated communicates with the actual vacuum space only via a single opening, which at the same time serves to pass the generated electrons. An additional advantage is that the caesium, which now remains practically completely enclosed in the space in which the cathode is situated exerts a gettering effect in this space, which guarantees a better vacuum and hence an increased stability especially of semiconductor cathodes arranged in this vacuum.

For the source of material reducing the electron work function, a carrier or holder provided with caesium azide may be chosen of the kind described in Netherlands Patent Application No. 8401866.

Preferably, however, a glass or metal reservoir is chosen for this purpose, which is filled with caesium and in which an opening can be provided, for example by means of a laser beam.

The invention will now by way of example be described more fully with reference to an embodiment and the drawing, which shows diagrammatically a part of an arrangement according to the invention.

The device 1 shown in the Figure comprises a vacuum space 2, in this example a vacuum tube with side walls 3 and an end wall 4. The device further comprises an electron-emitting body 5, in this embodiment a semiconductor cathode of the reverse biased junction type, as described in Netherlands Patent Application No. 7905470.

For a correct adjustment, the semiconductor cathode 5 is provided with connection wires 6, which can be applied via lead-through members 7 in the end wall 4 to such voltages that at the area of the surface 8 an electron current 9 is produced. In order to facilitate the emanation of the electrons produced in this case by avalanche multiplication, the surface 8 is preferably coated with a monoatomic layer of caesium.

During operation, however, this caesium layer can be partly lost, for example due to the etching ef-

fect of positive ions left in the vacuum tube or formed during operation. In thermionic cathodes, such a layer of material reducing the work function can be gradually lost by evaporation.

In order to compensate for this loss of caesium during operation, but also in order to provide, as the case may be, an initial layer of caesium, the arrangement 1 comprises according to the invention further a reservoir 10, which is composed of a first compartment 11 (whose wall consists in this embodiment partly of a metal wall 12 and partly of a glass wall 13) and of a second compartment 14.

The second compartment 14 has an end wall 15, which in this embodiment substantially coincides with a carrier 23 on the side of the vacuum space 2, while the side walls 16 of the second compartment 14 are connected via a weld 17 to the metal walls 12 of the first compartment 11. The compartments 11, 14 are separated from each other by an intermediate wall, which is provided with an opening 19, while the second compartment 14 communicates with the vacuum space 2 via one or more openings 20.

For the supply of caesium (or another material reducing the work function), the first compartment 11 accommodates, for example, a holder 21 consisting of glass or, as in the present embodiment, of a metal tube. Preferably, a nickel holder 21 is chosen for this purpose, which is filled with pure caesium 24.

The holder 21 can be opened from the outside, for example by means of a laser beam 31 of such a wavelength that the nickel or, as the case may be, a glass wall of the holder 21 melts, but the glass wall 13, which for this purpose is made of another kind of glass, remains unattacked. After the holder 21 has thus been provided with an opening 22, the caesium 24 has the opportunity to escape from the holder 21 in the vapour phase; this may further be promoted by the heat released upon melting of the glass window 22 or by means of heating elements (not shown).

Of the released caesium vapour, for example a part precipitates as liquid caesium 24 in the lower part of the first compartment 11. However, another part leaves this first compartment 11 via one or more openings 19 in the intermediate wall 18 between the first compartment 11 and the second compartment 14, which together constitute the reservoir 10. The caesium in the vapour phase, which moves, for example, along paths 25 shown diagrammatically, leaves in part the second compartment 14 via one or more openings 20 in the end wall 15 and thus reaches the vacuum space 2. The rate of evaporation of caesium deposited in the first compartment 11 and the speed of the caesium atoms (path 25) may be regulated, if required, by internally or externally provided temperature regulators 29 and 30. If desired, the flux of caesium through the walls 15 and 18 may also be made adjustable by making the size of the openings 20 and 19, respectively, variable.

By means of the temperature regulators 29, 30, which may consist, for example, of a combination of a strip resistor and a Peltier cooling element and, as the case may be, a heating diode, which may form part, if required, of the semiconductor cathode 5, it can be achieved that a stable non-critical equilibrium is obtained between the supplied caesium atoms

25 and the caesium atoms drained due to desorption or other phenomena. It has been found that in this manner the stability of the emission can be considerably increased, especially if the emitting body is arranged in a substantially closed space. Thus, a local caesium vapour pressure is obtained in this space, as a result of which a continuous dispensation of caesium atoms on the emitting surface is realized which leads to a high stability.

The substantially closed space is obtained in the present embodiment by means of an extraction grid 26 of practically cylindrical shape having an opening 27 allowing the generated electron beam 9 to pass. Moreover, this construction affords the advantage that the actual vacuum space 2 is not or substantially not contaminated with caesium, which has a favourable influence on the high-voltage properties of the vacuum tube and the elements present therein, such as deflection electrodes.

A continuous dispensation of caesium is possible in the arrangement 1, for example, by regulating the wall temperature of the walls of the reservoirs 11, 14 by means of the temperature regulators 29, 30.

The wall 15 of the second compartment 14 is preferably coated on the inner side with a gold layer. Caesium deposited on this wall forms with the gold caesium azide, which prevents caesium transport in the gap between the grid 26 and the wall 15 due to its low vapour pressure. The gold consequently has, as it were, a gettering effect. This may also be achieved, for example, with antimony. The gold layer may also be advantageously deposited on the inner wall of the extraction grid 26. It is also possible to apply a silver layer. This has the advantage that, after the vacuum device has been baked out, a surface practically free from oxide remains, as a result of which contamination of caesium is strongly reduced.

For the holder 21, alternatively a carrier with, for example, caesium azide (CsN_3) may be chosen, which dissociates during the thermal treatment, as described in Netherlands Patent Application No. 8401866 in the name of the Applicant. Preferably, however, pure caesium is chosen because no residual gases are then released. During operation of the arrangement described, no premature supply of caesium occurs either. For the reverse biased junction cathode, this results in a better reproducibility and a high initial efficiency.

Besides, the presence of pure caesium 24, 25 in the compartments 11, 14 and in the space within the grid 26 has a gettering effect. Thus, the vacuum is increased, as a result of which also the stability of the cathode 5 is further increased.

The electron-emitting body 5 need not necessarily be arranged on the wall 15, but may also be situated elsewhere in the vacuum space 2 or may be arranged at an oblique angle. When the cathode 5 is secured not on the end wall 15, but elsewhere on the carrier 23, the thermal coupling between the cathode and the reservoir 10 becomes smaller, which may be favourable in connection with the regulation of the supply of caesium. The exit openings 20 may then be provided, for example, in a side wall of the reservoir, which then projects further into the vac-

uum space. Other cathodes are also possible, such as, for example, field emitters, NEA cathodes or even thermionic cathodes, while the cathodes made of semiconductor material (silicon, gallium arsenide) may also form part of a larger semiconductor body, in which, for example, also electronic control circuitry is realized.

For the material reducing the electron work function, various other materials may also be chosen, such as potassium, rubidium, sodium or lithium, which is realised, for example, upon heating of a mixture or a compound in the holder/carrier 21.

The reservoir 10 may be made in one piece instead of in the form of two separate compartments, in which event the weld 17 is omitted.

The holder 21 need not necessarily be opened by means of a laser beam; this may be effected, if desired, by high-frequency energy, for example by means of a spring construction as described in US-PS No. 2,288,253.

Claims

1. An arrangement comprising a space which is evacuated or is filled with a protective gas, this arrangement comprising an electron-emitting body, which can be coated at an electron-emitting surface from a reservoir with material reducing the electron work function situated within the space, characterized in that the reservoir comprises two compartments, which communicate with each other *via* at least one opening in an intermediate wall, one compartment accommodating the source of material reducing the electron work function and the other compartment being provided with at least one exit opening, through which the material reducing the work function can leave the reservoir.

2. An arrangement as claimed in Claim 1, characterized in that the electron-emitting body is secured on the end wall of the reservoir.

3. An arrangement as claimed in Claim 1 or 2, characterized in that at least one of the compartments is provided with a temperature regulator.

4. An arrangement as claimed in any one of the preceding Claims, characterized in that the electron-emitting body is situated in a substantially closed space which is practically entirely separated from the vacuum space and communicates with the remaining part of the vacuum space *via* an opening in an extraction grid for the electrons to be generated.

5. An arrangement as claimed in Claim 4, characterized in that the outer wall of the reservoir around the exit opening or the extraction grid on the side facing the electron-emitting body is provided with a material having a gettering effect or a material whose oxide dissociates or desorbs at a temperature lower than the heating temperature of the arrangement.

6. An arrangement as claimed in Claim 5, characterized in that the outer wall of the reservoir around the exit opening or the extraction grid on the side facing the electron-emitting body is provided with a layer of one or more of the materials gold, antimony or silver.

7. An arrangement as claimed in any one of Claims 1 to 6, characterized in that the source of material reducing the electron work function is a holder filled with caesium.

8. A reservoir for an arrangement as claimed in any one of Claims 1 to 7, characterized in that the reservoir comprises two compartments, which communicate with each other *via* at least one opening in an intermediate wall, one compartment accommodating a source of material reducing the electron work function and the other compartment being provided with at least one exit opening.

9. A reservoir as claimed in Claim 8, characterized in that at least one of the compartments is provided with a temperature regulator.

10. A reservoir as claimed in Claim 8 or 9, characterized in that the outer wall of the reservoir is provided around the exit opening with a layer of one or more of the materials gold, antimony or silver.

Patentansprüche

1. Vorrichtung mit einem evakuierten oder mit einem Schutzgas gefüllten Raum, wobei diese Vorrichtung einen elektronenemittierenden Körper aufweist, der in diesem Raum an einer elektronenemittierenden Oberfläche aus einem Behälter mit einem elektronenaustrittspotentialverringern den Werkstoff bedeckt werden kann, dadurch gekennzeichnet, daß der Behälter zwei Abteile aufweist, die über wenigstens eine Öffnung in einer Trennwand miteinander in Verbindung stehen, wobei das eine Abteil die Quelle des elektronenaustrittspotentialverringern den Werkstoffes enthält und das andere Abteil mit wenigstens einer Austrittsöffnung versehen ist, durch die der elektronenaustrittspotentialverringern de Werkstoff den Behälter verlassen kann.

2. Vorrichtung nach Anspruch 1, dadurch gekennzeichnet, daß der elektronenemittierende Körper an der Endwand des Behälters befestigt ist.

3. Vorrichtung nach Anspruch 1 oder 2, dadurch gekennzeichnet, daß wenigstens eines der Abteile mit einem Temperaturregler versehen ist.

4. Vorrichtung nach einem der vorstehenden Ansprüche, dadurch gekennzeichnet, daß der elektronenemittierende Körper sich in einem im wesentlichen geschlossenen Raum befindet, der von dem Vakuumraum nahezu völlig getrennt ist und mit dem restlichen Teil des Vakuumraumes über eine Öffnung in einem Ausziehgitter für die zu erzeugenden Elektronen in Verbindung steht.

5. Vorrichtung nach Anspruch 4, dadurch gekennzeichnet, daß die Außenwand des Behälters um die Ausgangsöffnung oder das Ausziehgitter herum auf der dem elektronenemittierenden Körper zugewandten Seite mit einem Werkstoff mit einer Getterwirkung versehen ist, oder mit einem Werkstoff, dessen Oxid bei einer Temperatur unterhalb der Heiztemperatur der Vorrichtung dissoziiert oder desorbiert.

6. Vorrichtung nach Anspruch 5, dadurch gekennzeichnet, daß die Außenwand des Behälters um die Ausgangsöffnung oder das Ausziehgitter herum auf der dem elektronenemittierenden Körper zu-

uum space. Other cathodes are also possible, such as, for example, field emitters, NEA cathodes or even thermionic cathodes, while the cathodes made of semiconductor material (silicon, gallium arsenide) may also form part of a larger semiconductor body, in which, for example, also electronic control circuitry is realized.

For the material reducing the electron work function, various other materials may also be chosen, such as potassium, rubidium, sodium or lithium, which is realised, for example, upon heating of a mixture or a compound in the holder/carrier 21.

The reservoir 10 may be made in one piece instead of in the form of two separate compartments, in which event the weld 17 is omitted.

The holder 21 need not necessarily be opened by means of a laser beam; this may be effected, if desired, by high-frequency energy, for example by means of a spring construction as described in US-PS No. 2,288,253.

Claims

1. An arrangement comprising a space which is evacuated or is filled with a protective gas, this arrangement comprising an electron-emitting body, which can be coated at an electron-emitting surface from a reservoir with material reducing the electron work function situated within the space, characterized in that the reservoir comprises two compartments, which communicate with each other via at least one opening in an intermediate wall, one compartment accommodating the source of material reducing the electron work function and the other compartment being provided with at least one exit opening, through which the material reducing the work function can leave the reservoir.

2. An arrangement as claimed in Claim 1, characterized in that the electron-emitting body is secured on the end wall of the reservoir.

3. An arrangement as claimed in Claim 1 or 2, characterized in that at least one of the compartments is provided with a temperature regulator.

4. An arrangement as claimed in any one of the preceding Claims, characterized in that the electron-emitting body is situated in a substantially closed space which is practically entirely separated from the vacuum space and communicates with the remaining part of the vacuum space via an opening in an extraction grid for the electrons to be generated.

5. An arrangement as claimed in Claim 4, characterized in that the outer wall of the reservoir around the exit opening or the extraction grid on the side facing the electron-emitting body is provided with a material having a gettering effect or a material whose oxide dissociates or desorbs at a temperature lower than the heating temperature of the arrangement.

6. An arrangement as claimed in Claim 5, characterized in that the outer wall of the reservoir around the exit opening or the extraction grid on the side facing the electron-emitting body is provided with a layer of one or more of the materials gold, antimony or silver.

7. An arrangement as claimed in any one of Claims 1 to 6, characterized in that the source of material reducing the electron work function is a holder filled with caesium.

8. A reservoir for an arrangement as claimed in any one of Claims 1 to 7, characterized in that the reservoir comprises two compartments, which communicate with each other via at least one opening in an intermediate wall, one compartment accommodating a source of material reducing the electron work function and the other compartment being provided with at least one exit opening.

9. A reservoir as claimed in Claim 8, characterized in that at least one of the compartments is provided with a temperature regulator.

10. A reservoir as claimed in Claim 8 or 9, characterized in that the outer wall of the reservoir is provided around the exit opening with a layer of one or more of the materials gold, antimony or silver.

Patentansprüche

1. Vorrichtung mit einem evakuierten oder mit einem Schutzgas gefüllten Raum, wobei diese Vorrichtung einen elektronenemittierenden Körper aufweist, der in diesem Raum an einer elektronenemittierenden Oberfläche aus einem Behälter mit einem elektronenaustrittspotentialverringern den Werkstoff bedeckt werden kann, dadurch gekennzeichnet, daß der Behälter zwei Abteile aufweist, die über wenigstens eine Öffnung in einer Trennwand miteinander in Verbindung stehen, wobei das eine Abteil die Quelle des elektronenaustrittspotentialverringern den Werkstoffes enthält und das andere Abteil mit wenigstens einer Austrittsöffnung versehen ist, durch die der elektronenaustrittspotentialverringern den Werkstoff den Behälter verlassen kann.

2. Vorrichtung nach Anspruch 1, dadurch gekennzeichnet, daß der elektronenemittierende Körper an der Endwand des Behälters befestigt ist.

3. Vorrichtung nach Anspruch 1 oder 2, dadurch gekennzeichnet, daß wenigstens eines der Abteile mit einem Temperaturregler versehen ist.

4. Vorrichtung nach einem der vorstehenden Ansprüche, dadurch gekennzeichnet, daß der elektronenemittierende Körper sich in einem im wesentlichen geschlossenen Raum befindet, der von dem Vakuumraum nahezu völlig getrennt ist und mit dem restlichen Teil des Vakuumraumes über eine Öffnung in einem Ausziehgitter für die zu erzeugenden Elektronen in Verbindung steht.

5. Vorrichtung nach Anspruch 4, dadurch gekennzeichnet, daß die Außenwand des Behälters um die Ausgangsöffnung oder das Ausziehgitter herum auf der dem elektronenemittierenden Körper zugewandten Seite mit einem Werkstoff mit einer Getterwirkung versehen ist, oder mit einem Werkstoff, dessen Oxid bei einer Temperatur unterhalb der Heiztemperatur der Vorrichtung dissoziiert oder desorbiert.

6. Vorrichtung nach Anspruch 5, dadurch gekennzeichnet, daß die Außenwand des Behälters um die Ausgangsöffnung oder das Ausziehgitter herum auf der dem elektronenemittierenden Körper zu-



gewandten Seite mit einer Schicht aus einem oder mehreren der Werkstoffe Gold, Antimon oder Silber versehen ist.

7. Vorrichtung nach einem der Ansprüche 1 bis 6, dadurch gekennzeichnet, daß die Quelle des elektronenaustrittspotentialverringern den Werkstoffes eine mit Cäsium gefüllte Halterung ist.

8. Behälter für eine Vorrichtung nach einem der Ansprüche 1 bis 7, dadurch gekennzeichnet, daß der Behälter zwei Abteile aufweist, die über wenigstens eine Öffnung in einer Trennwand miteinander in Verbindung stehen, wobei das eine Abteil eine Quelle des elektronenaustrittspotentialverringern den Werkstoffes enthält und das andere Abteil mit wenigstens einer Ausgangsöffnung versehen ist.

9. Behälter nach Anspruch 8, dadurch gekennzeichnet, daß wenigstens eines der Abteile mit einem Temperaturregler versehen ist.

10. Behälter nach Anspruch 8 oder 9, dadurch gekennzeichnet, daß die Außenwand des Behälters um die Ausgangsöffnung herum mit einer Schicht aus einem oder mehreren der Werkstoffe Gold, Antimon oder Silber versehen ist.

Revendications

1. Dispositif muni d'un espace vidé d'air ou rempli d'un gaz protecteur, comportant un corps émetteur d'électrons qui peut être recouvert, selon une surface émettrice d'électrons d'un matériau réducteur du potentiel de sortie à partir d'un réservoir situé dans cet espace, caractérisé en ce que le réservoir comprend deux compartiments qui communiquent entre eux par au moins une ouverture dans une paroi intermédiaire, un compartiment contenant la source de matériau réducteur du potentiel de sortie et l'autre compartiment étant muni d'au moins une ouverture d'évacuation par laquelle le matériau réducteur du travail de sortie peut quitter le réservoir.

2. Dispositif selon la revendication 1, caractérisé en ce que le corps d'émetteur d'électrons est fixé à la paroi terminale du réservoir.

3. Dispositif selon la revendication 1 ou 2, caractérisé en ce qu'au moins l'un des compartiments est muni d'un régulateur de température.

4. Dispositif selon l'une des revendications précédentes, caractérisé en ce que le corps émetteur d'électrons se situe dans un espace pratiquement fermé qui est pratiquement entièrement séparé de l'espace à vide et qui communique avec une partie subsistante de l'espace à vide par l'intermédiaire d'une ouverture dans une grille d'extraction pour les électrons à engendrer.

5. Dispositif selon la revendication 4, caractérisé en ce que la paroi extérieure du réservoir autour de l'ouverture de sortie ou de la grille d'extraction sur la face située vis-à-vis du corps émetteur d'électrons est munie d'un matériau présentant un effet de getter ou un matériau dont l'oxyde est sujet à décomposition ou désorption à une température inférieure à la température de chauffage du dispositif.

6. Dispositif selon la revendication 5, caractérisé en ce que la paroi extérieure du réservoir autour

de l'ouverture de sortie ou de la grille d'extraction sur la face située vis-à-vis du corps émetteur d'électrons est munie d'une couche d'un ou de plusieurs des matériaux or, antimoine ou argent.

7. Dispositif selon l'une des revendications 1 à 6, caractérisé en ce que la source de matériau réducteur du potentiel de sortie est un support rempli de césium.

8. Réservoir pour un dispositif selon l'une des revendications 1 à 7, caractérisé en ce que le réservoir comporte deux compartiments qui communiquent entre eux par l'intermédiaire d'au moins une ouverture dans une paroi intermédiaire, un compartiment contenant une source de matériau réducteur du potentiel de sortie et l'autre compartiment étant muni d'au moins une ouverture de sortie.

9. Réservoir selon la revendication 8, caractérisé en ce qu'au moins l'un des compartiments est muni d'un régulateur de température.

10. Réservoir selon la revendication 8 ou 9, caractérisé en ce qu'autour de l'ouverture de sortie, la paroi extérieure du réservoir est munie d'une couche d'un ou de plusieurs des matériaux or, antimoine ou argent.

